

Attorney's Docket No.: 5353C1-459003
Client's Ref. No.: 5353/CMP

OFFICIAL COMMUNICATION
FACSIMILE
FOR THE PERSONAL ATTENTION OF:
EXAMINER SYLVIA R. MACARTHUR

GROUP 1763 FAX NO: (703) 872-9630

Number of pages including this page (38)

Applicant : Wallace T.Y. Tang
Serial No. : 09/134,147
Filed : August 14, 1998

Art Unit : 1763
Examiner : Sylvia R. MacArthur

FACSIMILE COMMUNICATION

Title : IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR
DETECTION OF THIN FILMS DURING CHEMICAL/MECHANICAL
POLISHING PLANARIZATION

Commissioner for Patents
Washington, D.C. 20231

Sir:

Attached to this facsimile communication cover sheet is a copy of the following documents:

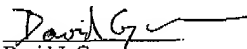
- o Copy of Allowed Claims from Application Serial No. 07/996,817 as of termination of interference on 02/25/2002;
- o Copy of 1.312 Amendment filed with the Issue Fee for Application Serial No. 07/996,817;
- o ~~Copy of Allowed Claims from Application Serial No. 09/134,147,~~
- o Copy of Preliminary Amendment filed with the RCE for Application Serial No. 09/134,147;

faxed this 30th day of **January**, 2003, to Group 1763, the United States Patent and Trademark Office.

Please note that we are trying to obtain the PCT/Reasons Statement and will forward upon receipt.

Respectfully submitted,

Date: January 30, 2003


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NOTE: This facsimile is intended for the addressee only and may contain privileged or confidential information. If you have received this facsimile in error, please immediately call us collect at (650) 839-5070 to arrange for its return. Thank you.

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Attorney's Docket No. 05542-459001 / 5353/CMP

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Wallace T.Y. Tang	Art Unit :	1763
Serial No. :	07/996,817	Examiner :	Thi Dang
Filed :	December 28, 1992	Confirmation No.:	2081
		Notice of Allowance Date: August 6, 2002	
Title :	IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR ENDPOINT DETECTION OF THIN FILMS DURING CHEMICAL/MECHANICAL POLISHING PLANARIZATION		

BOX ISSUE FEE

Commissioner for Patents
Washington, D.C. 20231

AMENDMENT UNDER 37 CFR 1.312

Please amend the application as issued below. This amendment is being filed concurrently with the payment of the issue fee.

In the Claims:

Please amend claims 59, 62, 68 and 82 as follows:

-- 59. (Amended) A method for producing a semiconductor device or a patterned layer intermediate, which comprises the steps of:

chemically mechanically polishing at least one layer on one side of the semiconductor device or patterned layer intermediate, wherein the layer is composed of a material selected from the group consisting of an insulating material, a semi-conducting material, a conducting material, and combinations thereof,

illuminating the side of the semiconductor device or patterned layer intermediate not being polished with light of a wavelength between about 1,000 nm and about 11,000

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, Washington, D.C. 20231.

November 6, 2002

Date of Deposit _____

Signature _____

Jennifer Leveille:

Typed or Printed Name of Person Signing Certificate